

Notice of References Cited	Application/Control No. 10/618,688		Applicant(s)/Patent Under Reexamination NATORI ET AL.	
	Examiner Christian Wilson		Art Unit 2824	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,316,801	11-2001	Amanuma, Kazushi	257/306
	B	US-6,201,726	03-2001	Evans, Thomas A.	365/145
	C	US-6,239,028	05-2001	Vaartstra, Brian A.	438/686
	D	US-5,530,667	06-1996	Omura et al.	365/145
	E	US-6,617,627	09-2003	Natori et al.	257/295
	F	US-6,518,168	02-2003	Clem et al.	438/623
	G	US-6,163,043	12-2000	Hirano et al.	257/296
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Okamura <i>et al.</i> , Fabrication of Ferroelectric Microcapacitors with Self-Aligned Top Electrodes by Electron-Beam-Induced Patterning Process, <i>Jpn. J. Appl. Phys.</i> , 41 (Nov 2002) 6754.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.